

The listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1 - 2. (Cancelled)

3. (Currently Amended) An apparatus for continuously preparing a silicon oxide powder, comprising
a charge feed means for feeding a raw material powder mixture containing silicon dioxide powder of a reaction chamber,
the reaction chamber where the raw material powder mixture is reacted to produce a silicon oxide gas,
a transfer ~~conduit line~~ for transferring the silicon oxide gas from the reaction chamber to a deposition chamber, the transfer conduit being equipped with a heater so as to maintain the conduit interior at a temperature from higher than 1,000°C to 1,300°C,
the deposition chamber in which a substrate provided with a coolant circuit is disposed and cooled at a temperature from 200°C to 500°C by a coolant in the coolant circuit so that silicon oxide deposits on a surface of the cooled substrate, and
a recovery means for recovering the silicon oxide deposit on the substrate.

4. (Currently Amended) An apparatus comprising
a feed mechanism capable of feeding a powder feed to a reaction furnace which is equipped with a heater,
a conduit from the reaction furnace to a deposition tank, said deposition tank, said conduit being equipped with a heater so as to maintain the conduit interior at a temperature from higher than 1,000°C to 1,300°C,
said deposition tank containing a substrate equipped with a cooling mechanism comprising a coolant circuit so as to cool the substrate at a temperature from 200°C to 500°C by a coolant in the coolant circuit, and
a product removal mechanism, which removes product deposited on the substrate.

5. (Previously Presented) An apparatus according to claim 4, further comprising a recovery tank connected to the deposition tank by a conduit.

6. (Previously Presented) An apparatus according to claim 4, wherein the product removal mechanism is a scraper.
7. (Currently Amended) An apparatus according to claim 4, wherein the feed mechanism comprises a hopper, a feeder and a feed tube.
8. (Cancelled)
9. (Previously Presented) An apparatus according to claim 4, wherein the substrate is disposed horizontally.
10. (Previously Presented) An apparatus according to claim 7, wherein a vacuum pump is connected to the hopper, the deposition tank and/or the recovery tank.
11. (Previously Presented) An apparatus according to claim 3, wherein the feed charge means comprises a hopper, a feeder and a feed tube.
12. (Cancelled)
13. (Previously Presented) An apparatus according to claim 3, wherein the recovery means comprises a scraper.
14. (Cancelled)
15. (New) An apparatus according to claim 3, further comprising a recovery tank connected to the deposition tank by a conduit.
16. (New) An apparatus according to claim 3, wherein the substrate is disposed horizontally.
17. (New) An apparatus according to claim 16, wherein a vacuum pump is connected to the hopper, the deposition tank and/or the recovery tank.